# UNSTABLE RESONATOR SEMICONDUCTOR LASERS

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**Conference Paper** 

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NUMBER PERSON OF ABSTRACT OF PAGES Dr. Andrew Ongstad c. THIS PAGE 19b. TELEPHONE NUMBER (include a. REPORT b. ABSTRACT area code) Unclassified Unclassified Unclassified Unlimited 19 (505) 853-3207

17. LIMITATION

Optically pumped semiconductor lasers, antimonides, W lasers, mid-IR semiconductor lasers, unstable resonators

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19a, NAME OF RESPONSIBLE

# Unstable Resonator Semiconductor Lasers

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Opening intro chart

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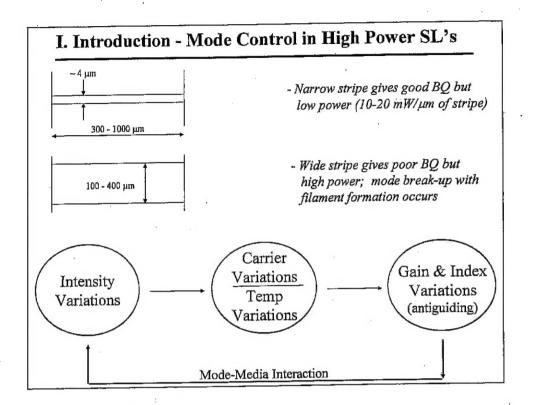
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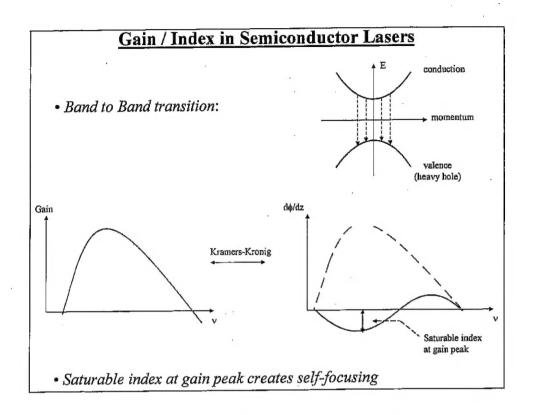
# Outline

- I. Introduction
  - Mode Control in High-Power Semiconductor Lasers
  - Mode-Media Interactions (Filament Formation)
- II. Suppressing Filaments
- III. Unstable Resonators for semiconductor lasers.
- IV. Summary & Outlook

We will read the chart, we will offer some of the history of filament formation.



This chart describes the mechanisms of mode-media interaction in broad-area semiconductor lasers.

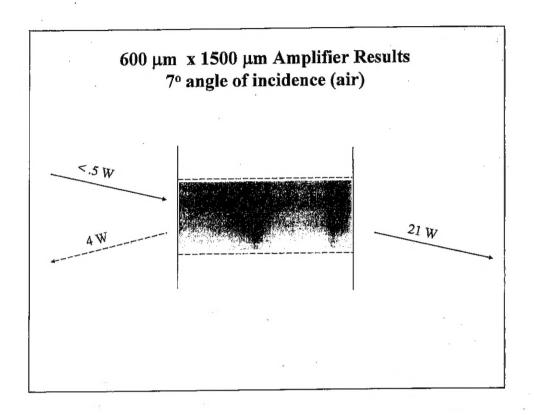


This chart shows the asymmetric gain versus frequency curve for a typical band—to—band transition. This asymmetry leads to saturable index of refraction at the gain peak, the origin of self-focusing.

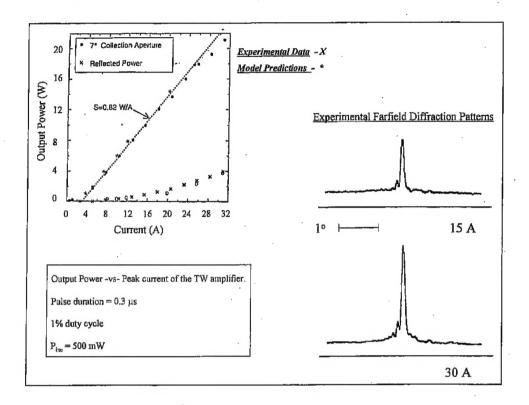
# Several research groups have observed that tilted amplifiers can provide high-gain as well as good BQ: R-0 R-1 RWA R-0 R-0 R-1

We will discuss the experiments on tilted semiconductor amplifiers that were done between 1990 -1995.

**TWA** 



This chart shows the configuration for a TWA, that provided 21 Watts of diffraction limited output power in a 1992 experiment.



These are the published results from that experiment.

# **Beam Propagation Method**

Paraxial wave equation in the diode with filamentation tendencies given by α-parameter

$$\frac{1}{2ik} \frac{\partial^2 U}{\partial x^2} + \frac{\partial U}{\partial z} = \frac{\Gamma G(N(x,z))}{2} \cdot (1 - i\alpha) \cdot U$$

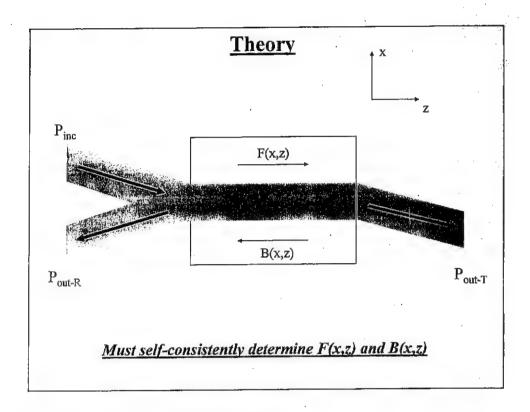
$$(\alpha - \text{linewidth enhancement factor})$$

$$U(x,z) = F(x,z)$$
 or  $B(x,z)$ 

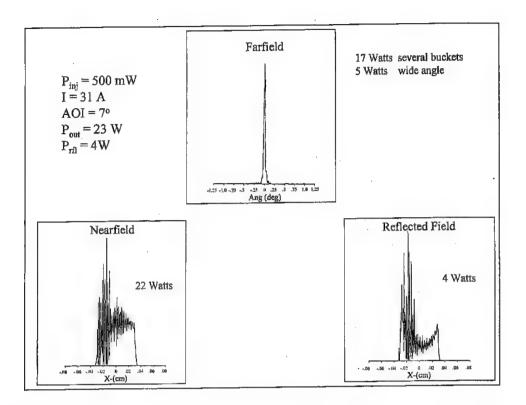
Carrier diffusion in the diode

$$D_e \frac{\partial^2 N}{\partial x^2} - \frac{N}{\tau_s} - \frac{G}{h\nu} \cdot \left(I_f + I_b\right) + \frac{\eta J}{qW_a} = 0$$

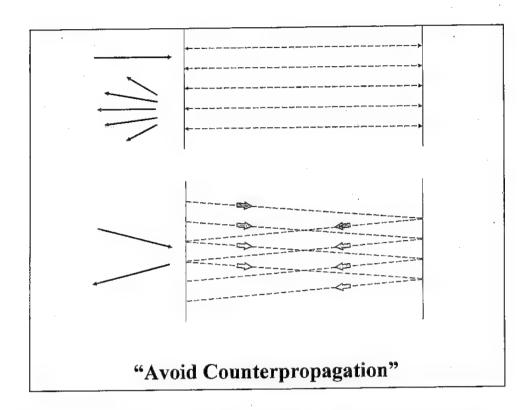
Wave optics modeling of semiconductor lasers or amplifiers requires simultaneous self-consistent solutions of the wave equation and the carrier diffusion equation.



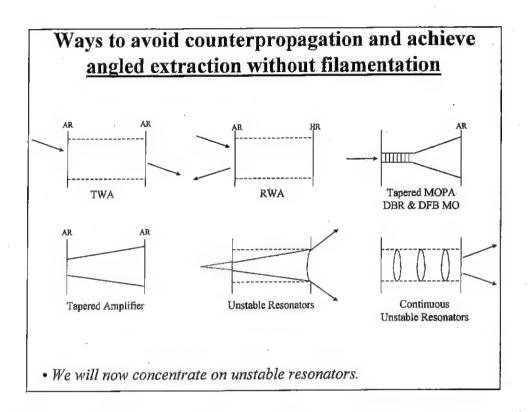
This figure shows our modeling geometry.



These are our simulation results, showing excellent agreement with the 1992 experiment.



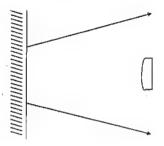
This chart illuminates the substantial benefits realized by angled extraction.



All of these resonator configurations essentially avoid exact counterpropagation and offer promise for high power and good beam quality.

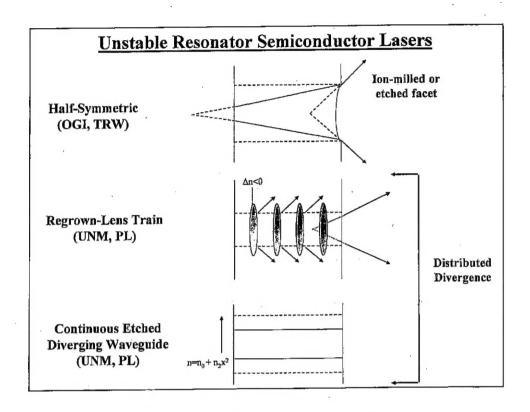
### III. Unstable Resonators

• Invented by A. Siegman



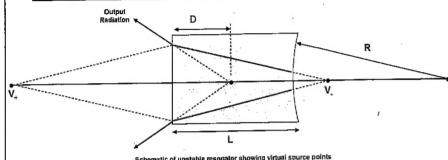
- Large mode volumes
- Near diffraction limited performance (good mode discrimination)
- Insensitive to misalignments and aberrations in the medium
- Avoids exact counterpropagation and suppresses filaments
- · Applications to semiconductor lasers
  - Bogatov, et.al. (1980) polished facet mirror
  - Craig, PhD Disseration (1985) etched facet mirrors
  - Yariv, Salzman, et.al. (1985-87) etched facet mirrors
  - Tilton, Dente, et.al. (1989-present) ion milled, etched, lens train

The unstable resonator has a long history and we will essentially cover that here.



These are the types of unstable resonators that have been implemented on semiconductor lasers.

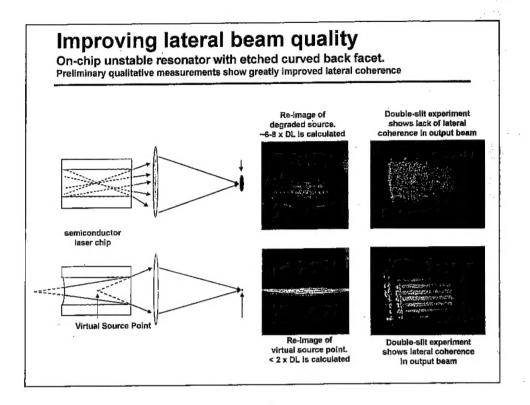
### High-Brightness from an Unstable Resonator Mid-IR Semiconductor Laser



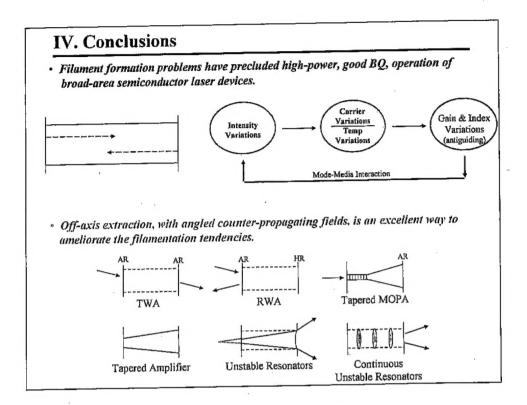
- Schematic of unstable resonator showing virtual source points
- Two virtual mode source points located at distances  $V=\pm\sqrt{L^2+L\,R}$ from the flat facet; L = 3.4 mm, R = 7.5 mm, V/n = 1.6 mm.
- The left virtual source, V<sub>+</sub>, is at an object distance (V+L) from the diverging mirror with focal length (-R/2). Upon reflection from the curved facet, the radiation forms a virtual image, V, at a distance (V-L) to the right of the curved facet. These distances satisfy the imaging equation:

This chart illustrates the unstable resonator that we used in our recent experiment on optically pumped mid-ir semiconductor lasers.

We will read through this chart.



This chart shows the farfields of both a Fabry-Perot resonator and our unstable resonator. The right hand pictures show farfield interference when a double slit is inserted into the near field.



This final chart reviews the essential physics of mode-media interaction and filament formation, in addition it recalls the basic methods for obtaining high power and suppressing filaments.